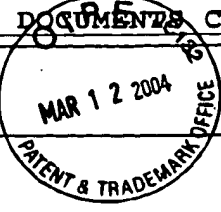














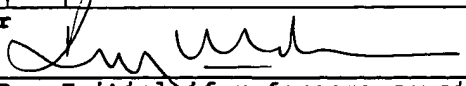


FORM PTO-1449				Atty. Docket No. XA-9387		Appln. No. 09/714,183	
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	AR	Freitag et al., "Wavefront analysis of photolithographic lenses," JR, 1/1991, pp. VIII-XII.					
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Examiner 				Date Considered 06/17/2004			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							